

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of)	ATOMIC LAYER DEPOSITION
)	METHOD AND SEMICONDUCTOR
Hwang et al.)	DEVICE FABRICATING
)	APPARATUS HAVING ROTATABLE
Application No.)	GAS INJECTORS
)	Group Art Unit:
Filing Date:)	
		Examiner:

Commissioner for Patents
P.O. Box 1450
Mail Stop: Divisional Patent Application
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

Applicant hereby submits the following Preliminary Amendment to the above-referenced application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 5 of this paper.